

OPTICAL AND SENSITIVE
PROPERTIES OF NANOSTRUCTURED SILICON
IRRADIATED WITH HIGH-ENERGY PARTICLES
(PROTONS, α -PARTICLES, AND HEAVY IONS)

*N.L. Dmitruk*¹, *O.S. Kondratenko*¹, *M.B. Pinkovska*²,
*V.I. Khivrich*², *L.A. Vlasukova*³, *P.V. Kuchynsky*³

¹V.E. Lashkaryov Institute of Semiconductor Physics,
Nat. Acad. of Sci. of Ukraine
(41, Nauky Ave., Kyiv 03028, Ukraine;
e-mail: kondratenko@isp.kiev.ua),

²Institute for Nuclear Research,
Nat. Acad. of Sci. of Ukraine
(47, Nauky Ave., Kyiv 03680, Ukraine),

³Belarussian State University
(7, Kurchatov Str., Minsk, 220064, Belarus)

S u m m a r y

For gas sensorics needs, an attempt has been made to modify a silicon surface by accelerated charged particles which form tracks. The influence of irradiation with 6.8-MeV protons, 27.2-MeV α -particles, and heavy ions (⁴⁰Ar, ¹³¹Xe, and ²⁰⁹Bi) on the optical and adsorption properties of *n*-Si and SiO₂/Si structures with nanopores has been studied. Scanning electron microscopy and atomic-force microscopy were used to analyze the surface morphology. The optical constants *n* and *k* of specimens before and after irradiation were determined making use of multiangle monochromatic ellipsometry. The modification of optical constants of *n*-Si specimens subjected to the *p*⁺ or α -particle irradiation was found to be caused by the destruction of a near-surface layer of the material and to be accompanied by an enhancement of the surface roughness. The irradiated structures revealed a higher sensitivity to the adsorption of ammonia and acetone molecules. The optical constants of SiO₂/Si structures were shown to depend on the material porosity. The fill factor of a SiO₂ layer irradiated with ¹³¹Xe and ²⁰⁹Bi ions was calculated. The most developed pore surface was found after the irradiation of silicon with ²⁰⁹Bi ions. Accordingly, the largest changes of optical constants were observed in specimens irradiated with bismuth ions.